

Abstract of the Disclosure

A vapor deposition device for vapor deposition of vertically aligned regions of a substrate has an upright, electrically heated melting crucible having an electrical heater for the material to be vaporized. A nozzle pipe, which is separate from the melting crucible and is sealable on top, having a vapor outlet for vapor deposition of the substrate, is seated on the melting crucible. The nozzle pipe has a heater which is independent of the heater of the melting crucible.